



Docket No. 1232-4590US2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Kazutaka YANAGITA, et al.

Serial No. : 10/639,460

Art Unit: To be assigned

Filed : August 13, 2003

Examiner: To be assigned

For : SAMPLE PROCESSING SYSTEM

SECOND SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to Rule 56, Applicants hereby call the attention of the Patent Office to the references listed on the attached Form PTO 1449. The attached Form PTO-1449 is to replace the PTO-1449 Forms filed on September 15, 2003 and August 13, 2003, to correct minor typographical errors in items BU and BV. Copies of these references ☒ are not attached & ☒ were filed or cited in parent application U.S. Serial No(s) 10/153,608, filed May 24, 2002, 09/434,741 filed November 5, 1999, and 09/435,285 filed November 5, 1999.

- ☐ This document is being filed within three (3) months of the filing date of the application
- ☐ A check for the requisite fee of \$180 is enclosed.
- ☐ This document is being concurrently filed with the above-identified application
- ☐ This document is being concurrently filed with an Request for Continued Examination (RCE)
- ☒ This document is being filed prior to a first Office Action
- ☐ This document is accompanied by a Search Report/Communication cited in a corresponding PCT or foreign counterpart application.
- ☒ The Commissioner is hereby authorized to charge any additional fees which may be required for this Information Disclosure Statement, or credit any overpayment to Deposit Account No. 13-4503, Order No. 1232-4590US2.

Respectfully submitted,
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Dated: November 17, 2003

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FORM PTO-1449

INFORMATION DISCLOSURE CITATION

Attorney Docket:
1232-4590US2

Serial No.:
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Applicants:
Yanagita et al.

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Group Art Unit:
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U.S. PATENT DOCUMENTS

Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	AA	3,493,155	02/03/70	Irving Litant et al.	225	2	
	AB	3,549,446	12//22/70	R.W. Bennett et al.	156	230	
	AC	3,667,661	06/06/72	Farmer	225	2	
	AD	3,730,410	05/01/73	Altshuler	225	96.5	
	AE	4,962,879	10/16/90	Goessele et al.	156	281X	
	AF	5,100,544	03/31/92	Izutani, et al.	210	75	
	AG	5,255,853	10/26/93	Munoz	83	177X	
	AH	5,374,564	12/20/94	Bruel	437	24	
	AI	5,379,235	01/03/95	Fisher et al.	364	508	

FOREIGN PATENT DOCUMENTS

Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	AJ	KR 1998-33377	0/75/98	Korean			<input type="checkbox"/> Yes <input type="checkbox"/> No
	AK	EP 0 709 876 A1	05/01/96	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No
	AL	EP 0 840 381 A2	05/06/98	Europe			<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
	AM	EP 0 843 345 A2	5/20/98	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No

OTHER DOCUMENTS (Including Author, Title, Date, etc.)

AN	"Single-Crystal Silicon on Non-Single-Crystal Insulators", G.W. Cullen, <u>Journal of Crystal Growth</u> , Vol. 63, No. 3, pp. 429-590, 1983
AO	"Crystalline Quality of Silicon Layer Formed by FIPOS Technology", Kazuo IMAI et al., <u>Journal of Crystal Growth</u> , Vol. 63, pp 547-553, 1987
AP	"Silicon-On-Insulator by Wafer Bonding: A Review", W.P. Maszara, <u>Journal of Electrochemical Society</u> , Vol. 138, pp. 341-347, 1991

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP §609.

Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to Applicant.



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U.S. PATENT DOCUMENTS

Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	AQ	5,510,019	4/23/96	Yabumoto et al.	210	137	
	AR	5,747,387	05/05/98	Koizumi et al.	438	906X	
	AS	5,783,022	07/21/98	Cha et al.	156	344	
	AT	5,849,602	12/15/98	Okamura et al.	438	908X	
	AU	5,876,497	03/02/99	Atoji	117	85	
	AV	5,928,389	7/27/99	Jevtic	29	25.01	
	AW	5,934,856	08/10/99	Asakawa et al.	414	217	
	AX	5,994,207	11/30/99	Henley et al.	438	515	02/19/98
	AY	6,122,566	09/19/00	Nguyen et al.	438	908X	03/03/98

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Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	AZ	EP 0 999 578 A2	05/10/00	Europe			<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
	BA	EP 1 026 729 A2	08/09/00	Europe			<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
	BB	EP 1 045 448 A1	10/18/00	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No
	BC	EP 0 926 719 A2	06/30/99	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No

OTHER DOCUMENTS (Including Author, Title, Date, etc.)

BD	"Light Scattering Topography Characterization of Bonded SOI Wafer", H. Baumgart, et al., <u>Extended Abstracts</u> , Vol. 91-2, pp. 733-734, 1991
BE	"Thinning of Bonded Wafer: Etch-Stop Approaches", Charges E. Hunt et al., <u>Extended Abstracts</u> , Vol. 91-2, pp. 696-697, 1991
BF	"Epitaxial Layer Transfer by Bond and Etch Back of Porous Si", Takao Yonehara et al., <u>Applied Physics Letters</u> , Vol. 64, pp. 2108-2110, 1994

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U.S. PATENT DOCUMENTS

Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	BG	6,221,740	4/24/01	Bryan et al.	438	458	
	BH	6,277,234 B1	8/21/01	Freund et al.	156	344	
	BI	6,321,134 B1	11/20/01	Henley et al.	700	121	11/20/01
	BJ	5,570,994	11/5/1996	Somekh et al.	414	786	5/10/1995
	BK	2,191,513	2/27/40	W. P. Bigelow	141	7	3/13/37
	BL	2,517,394	8/1/50	Z. U. Le Tellier	134	80	2/19/45
	BM	3,094,207	6/18/63	R. G. Millhiser et al.	198	209	5/24/61
	BN	3,489,608	1/13/70	B. Jacobs et al.	134	25	10/26/65
	BO	3,970,471	7/20/76	Bankes et al.	134	6	4/23/75

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Examiner Initial		Document Number	Publication Date	Country	Class	Sub-Class	Translation
	BP	5-21338	1/29/93	Japan			English Abstract
	BQ	7-302889	11/14/95	Japan			English Abstract
	BR	WO 99/06110	02/11/99	WO			<input type="checkbox"/> Yes <input type="checkbox"/> No
	BS	WO 01/04933	01/18/01	WO			<input type="checkbox"/> Yes <input type="checkbox"/> No
	BT	WO 01/10644 A1	02/15/01	WO			<input type="checkbox"/> Yes <input type="checkbox"/> No

OTHER DOCUMENTS (Including Author, Title, Date, etc.)

	BU	"Electrolytic Shaping of Germanium and Silicon", A. Uhlir et al., <u>Bell System Technical Journal</u> , Vol. 35, pp. 333-347, 1956
	BV	"Oxidized Porous Silicon and It's Application", K. Nagano et al., <u>The Transactions of the Institute of Electronics and Communication Engineers. The Institute of Electronics, Information and Communication Engineers</u> , Vol. 79, pp. 49-54, SSD 79-9549, 1979
	BW	"A New Dielectric Isolation Method Using Porous Silicon", K. Imai, <u>Solid-State Electronics</u> , Vol. 224, pp. 159-164, 1981

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Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	BX	4,047,973	9/13/77	Williams	134	10	10/27/76
	BY	4,208,760	6/24/80	Dexter et al.	15	302	12/19/77
	BZ	4,215,928	8/5/80	Bayley et al.	354	319	3/30/79
	CA	4,850,381	7/25/89	Moe et al.	134	62	2/1/88
	CB	5,248,886	9/28/93	Asakawa et al.	250	442.11	2/27/92
	CC	5,357,645	10/25/94	Onodera	15	97.1	5/14/93
	CD	5,653,247	8/5/1997	Murakami	134	80	8/14/95
	CE	5,679,405	10/21/97	Thomas et al.	427	248.1	7/24/95
	CF	5,792,709	8/11/98	Robinson et al.	438	692	12/19/95

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Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	CG	JPA 56-30650	3/27/81	Japan			Abstract Only
	CH	JPA60-05530	1/14/94	Japan			English Abstract
	CI	JPA4-293236	10/16/92	Japan			English Abstract

OTHER DOCUMENTS (Including Author, Title, Date, etc.)

CJ	"Silicon on Insulator Material by Wafer Bonding", Christine Harendt, Charles E. Hunt et al., <i>Journal of Electronic Materials</i> , vol. 20, pp. 267-277, 1991
CK	Michel Bruel, et al. "Smart-Cut: A New Silicon On Insulator Material Technology Based On Hydrogen Implantation And Wafer Bonding", <i>Jpn. J. Appl. Phys. Vol. 36, No. 3B, Part 01, March 1, 1997, pages 1636-1641</i>
CL	U.S. Application Serial No. 09/399,643, filed September 20, 2002, entitled "Separating Apparatus and Method, and Substrate Manufacturing Method."

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Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	CM	5,795,401	8/18/98	Itoh et al.	134	6	10/10/96
	CN	5,810,028	9/22/98	Ichikawa et al.	134	66	6/12/97
	CO	5,820,329	10/13/98	Derbinski et al.	414	225	4/10/97
	CP	5,954,888	9/21/99	Gupta et al.	134	3	2/9/98
	CQ	6,007,675	12/28/99	Toshima	156	345	12/1/97
	CR	6,168,499	1/2/2001	Jang	451	8	5/18/99
	CS	4,915,564	4/10/90	Error et al.	414	217	7/20/98
	CT	6,131,589	10/17/00	Vogtmann et al.	134	113	2/9/99
	CU	6,382,292	5/7/02	Ohmi et al.	156	584	3/25/98
	CV	6,418,999	7/16/02	Yanagita et al.	156	584	12/15/98
	CW	6,527,031	3/4/03	Yanagita et al.	156	584	11/5/99

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Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	CX	JPA63-16455	11/15/94	Japan			English Abstract
	CY	JPA9-167724	6/24/97	Japan			English Abstract
	CZ						<input type="checkbox"/> Yes <input type="checkbox"/> No

OTHER DOCUMENTS (Including Author, Title, Date, etc.)

	DA	U.S. Application Serial No. 09/434,740, filed November 11, 2002, entitled "Sample Separating Apparatus and Method."
	DB	US Application No. 09/434,663, filed November 5, 1999, entitled "Sample Processing System," to K. Yanagita et al.
	DC	"History of Water Jet Machining Development", Journal of the Water Jet Technology Society of Japan, vol. 1, No. 1, pages 4-15, 1984

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